

Substitute Form PTO-1449 (Modified)  <b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977/263001/US4563	Application No. Unknown
	Applicant Yamazaki, et al.		
	Filing Date Filed Herewith	Group Art Unit	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
q2	AA	5,757,456	5/26/98	Yamazaki, et al.	—	—	
1	AB	5,821,138	10/13/98	Yamazaki, et al.	—	—	
1	AC	5,834,327	11/10/98	Yamazaki, et al.	—	—	
q2	AD	6,118,502	9/12/00	Yamazaki, et al.	—	—	
	AE						
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial...	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation
							Yes No
q2	AH	8-96959	4/12/96	Japan	—	—	Abstract only
	AI	9-63770	3/7/97	Japan	—	—	Abstract only
	AJ	9-312260	12/2/97	Japan	—	—	Abstract only
	AK	10-247735	9/14/98	Japan	—	—	Abstract only
	AL	10-270363	10/9/98	Japan	—	—	Abstract only
	AM	11-191628	7/13/99	Japan	—	—	Abstract only
	AN	8-254686	10/1/96	Japan	—	—	Abstract only
q2	AO	8-288522	11/1/96	Japan	—	—	Abstract only

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
q2	AP	Shimoda, et al., "Surface Free Technology by Laser Annealing (SUFTLA)", IEDM Technical Digest, 1999, pp.289-292.
	AQ	
	AR	
	AS	

Examiner Signature <i>qoh ap</i>	Date Considered 2/24/03
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	